

Docket No.: 50063-064

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Application of
Shunichi SHIOMI, et al.

Serial No.: 10/086,877

Group Art Unit: 2621

Filed: March 04, 2002

Examiner: not yet assigned

For: DETECTION OF AN END POINT OF POLISHING A SUBSTRATE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

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In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

The relevance of each non-English language reference, if any, is discussed in the present specification.

Respectfully submitted,

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**INFORMATION DISCLOSURE
CITATION IN AN
APPLICATION**

ATTY. DOCKET NO.
50063-064

SERIAL NO.
10/086,877

APPLICANT
Junichi SHIOMI, et al.

FILING DATE
March 04, 2002

GROUP
2621

(PTO-1449)

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE

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FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
	9-131663	05/20/1997	Japanese (w/English Abstract)				
	3001051	12/11/1999	Japanese(w/English Abstract No. 11-58225)				

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.